

FIG. 1A

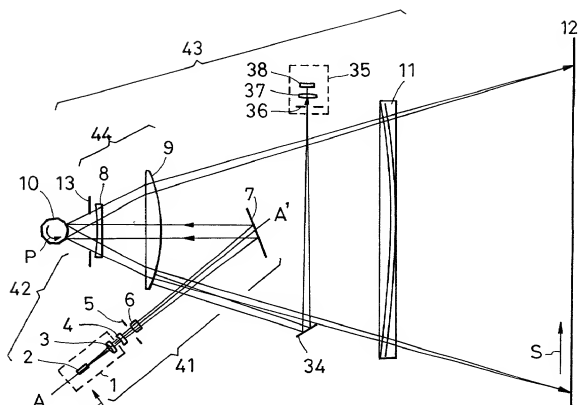


FIG. 1B



FIG. 1C

SECTION TAKEN ALONG LINE AA'

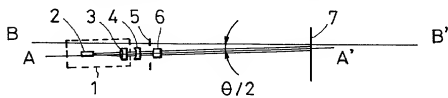


FIG. 2

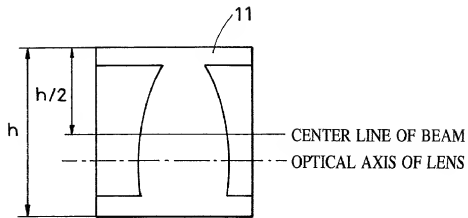


FIG. 3A

WITH SEMICONDUCTOR LASER CHIP NOT TILTED

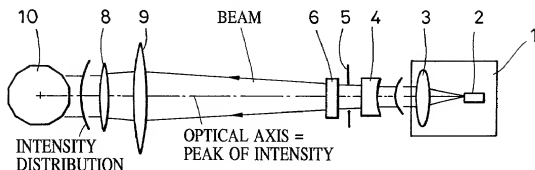


FIG. 3B

WITH SEMICONDUCTOR LASER CHIP TILTED

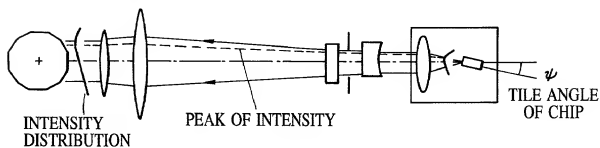


FIG. 3C

WITH SEMICONDUCTOR LASER CHIP SHIFTED

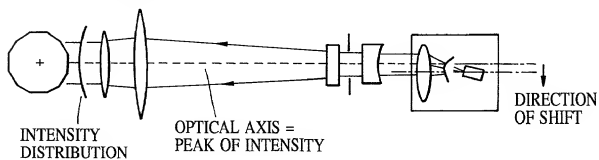


FIG. 4A

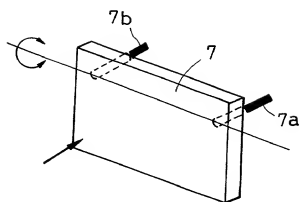


FIG. 4B

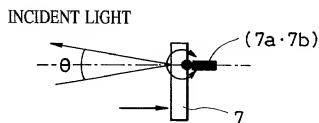


FIG. 5A

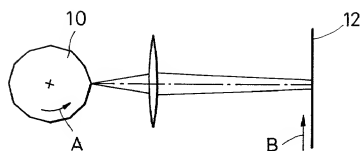


FIG. 5B

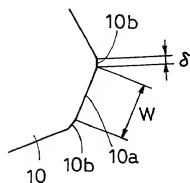


FIG. 6

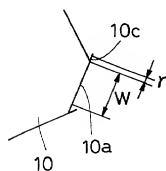


FIG. 7A

FIG. 7B

FIG. 7C

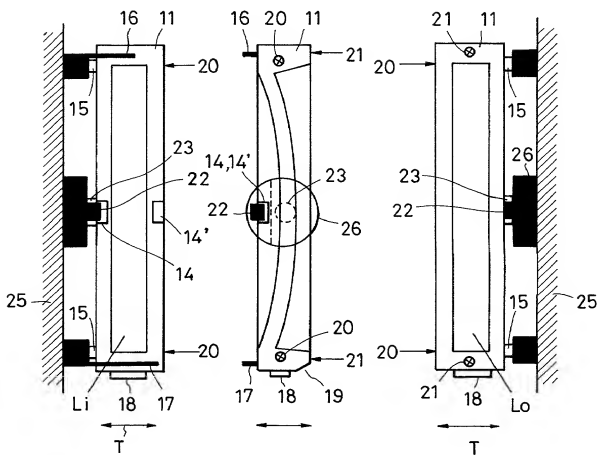


FIG. 7D

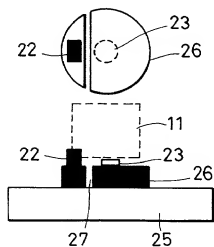


FIG. 8

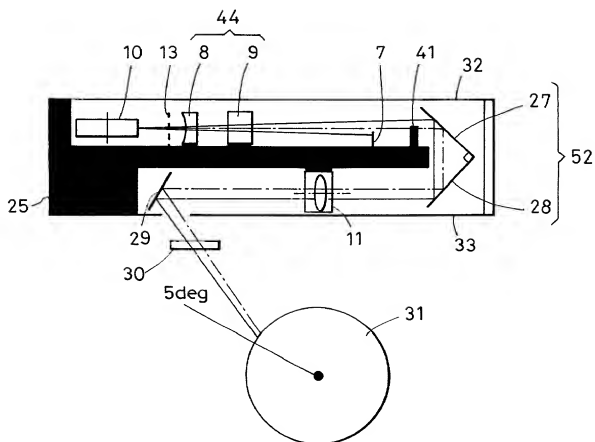


FIG. 9A

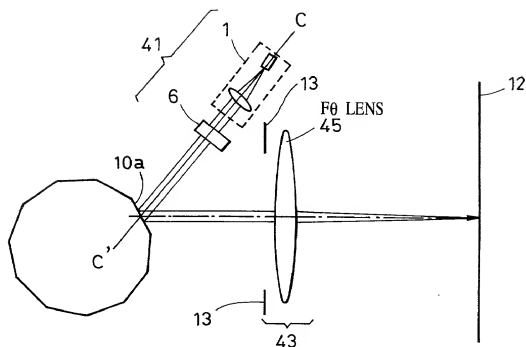


FIG. 9B

SECTION IN SUB-SCAN OPERATION TAKEN ALONG LINE CC'

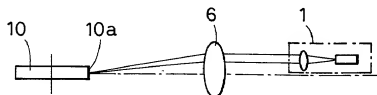




FIG. 10

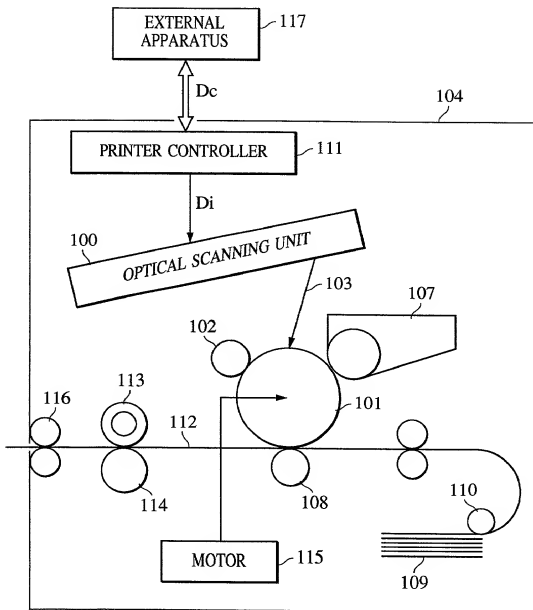


FIG. 11

